



Attorney Docket No. 5649-1226

PATENT

AG  
IPW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: **Kim et al.**

Serial No.: **10/806,521**

Filed: **March 23, 2004**

For: **METHOD OF FABRICATING A SEMICONDUCTOR SUBSTRATE FOR  
REDUCING WAFER WARPAGE**

Confirmation No.: **2748**

Group Art Unit: **2812**

Examiner: **Walter Lee Lindsay, Jr.**

Date: May 16, 2006

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION**

Sirs:

Applicants provide the present Amendment to address the issues raised in the Final Office Action mailed February 22, 2006 (the Action).

It is not believed that an extension of time and/or additional fee(s), including fees for additional claims, are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

Amendments to the claims begins on page 2 of this paper.

Remarks begin on page 6 of this paper.